

Substitute for forms 1449A/PTO & 1449B/PTO

ATTORNEY'S DKT NO.
024445-377APPLICATION NO.
10/653,244INFORMATION DISCLOSURE
STATEMENT BY APPLICANTAPPLICANT
Anders HÖRLING et al.FILING DATE
September 3, 2003GROUP
1772

U.S. PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
<i>A</i>	5,272,014		LEYENDECKER et al.	12-21-1993
<i>A</i>	5,330,853		HOFMANN et al.	07-19-1994
<i>A</i>	5,503,912		SETOYAMA et al.	04-02-1996
<i>A</i>	5,981,049		OHARA et al.	11-09-1999
<i>A</i>	6,077,596		HASHIMOTO et al.	06-20-2000
<i>A</i>	6,103,357		SELINDER et al.	08-15-2000
<i>A</i>	6,254,984	B1	IYORI	07-03-2001
<i>A</i>	6,309,738	B1	SAKURAI	10-30-2001
<i>A</i>	2002/0081161	A1	YAMADA et al.	06-27-2002

FOREIGN PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Country	Date of Publication (MM-DD-YYYY)	Translation Yes No
<i>A</i>	1 219 723	A2	EP	07-03-2002	
<i>A</i>	11310867		JP	11-09-1999	
<i>A</i>	9295204		JP	11-18-1997	

NONPATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
<i>A</i>	Hermann A. Jehn et al., MORPHOLOGY AND PROPERTIES OF SPUTTERED (Ti,Al)N LAYERS ON HIGH SPEED STEEL SUBSTRATES AS A FUNCTION OF DEPOSITION TEMPERATURE AND SPUTTERING ATMOSPHERE, J. Vac. Sci. Technol. A 4 (6), 2701 (1986)
<i>A</i>	O. Knotek et al., ON STRUCTURE AND PROPERTIES OF SPUTTERED TI AND AL BASED HARD COMPOUND FILMS, J. Vac. Sci. Technol. A 4 (6), 2695 (1986)
<i>A</i>	B.-J. Kim et al., HIGH TEMPERATURE OXIDATION OF (Ti _{1-x} Al _x)N COATINGS MADE BY PLASMA ENHANCED CHEMICAL VAPOR DEPOSITION, J. Vac. Sci. Technol. A 17(1), 133 (1999)
<i>A</i>	W.-D. Münz, TITANIUM ALUMINIUM NITRIDE FILMS - A NEW ALTERNATIVE TO TIN COATINGS, Int. Conf. Met. Coat., San Diego, USA (1986)
<i>A</i>	Harland G. Tompkins, OXIDATION OF TITANIUM NITRIDE IN ROOM AIR AND IN DRY O ₂ , J. Appl. Phys. 70 (7), 3876 (1991)
<i>A</i>	D. McIntyre et al., OXIDATION OF METASTABLE SINGLE-PHASE POLYCRYSTALLINE Ti _{0.5} Al _{0.5} N FILMS: KINETICS AND MECHANISMS, J. App. Phys. 67 (3), 1542 (1990)
<i>A</i>	H. Holleck, METASTABLE COATINGS - PREDICTION OF COMPOSITION AND STRUCTURE, Surf. and Coat. Technol. 36, 151 (1988)

Examiner
SignatureDate
Considered

9/05

EXAMINER: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. SEND TO: Assistant Commissioner for Patents, Washington, DC 20231.

SECOND INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet

1

of

Complete if Known

Application Number

10/653,244

Filing Date

September 3, 2003

First Named Inventor

Horling, Anders et. al.

Examiner Name

Unassigned

Attorney Docket Number

024445-377

MAR 24 2004

U.S. PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Name of Patentee or Applicant of Cited Document	Issue/Publication Date (MM-DD-YYYY)
A	2002/028323	A1	NAKAMURA et al.	03-07-2002

FOREIGN PATENT DOCUMENTS

Examiner Initials	Document Number	Kind Code (if known)	Country	Date of Publication (MM-DD-YYYY)	Translation	
					Yes	No

NON-PATENT LITERATURE DOCUMENTS

Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
A	L. KARLSSON et al., "Influence of residual stresses on the mechanical properties of TiC_xN_{1-x} ($x = 0, 0.15, 0.45$) thin films deposited by arc evaporation", <i>Thin Solid Films</i> , 371 (2000) pp. 167-177.
S	S. MENZEL et al., "Phase transitions in PACVD-(Ti,Al)N coatings after annealing", <i>Surface and Coatings Technology</i> , 124 (2000), pp. 190-195.

Examiner
Signature

Date

Considered

9/05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.